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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/673,873	09/30/2003	Sung-Bae Lee	SEC.1084	2344
20987 7	590 05/17/2005		EXAMINER	
VOLENTINE FRANCOS, & WHITT PLLC			ESTRADA, MICHELLE	
ONE FREEDO	M SQUARE			<u> </u>
11951 FREED	OM DRIVE SUITE 1260		ART UNIT	PAPER NUMBER
RESTON, VA 20190		2823		

DATE MAILED: 05/17/2005

Please find below and/or attached an Office communication concerning this application or proceeding.

			MI			
	Application No.	Applicant(s)				
	10/673,873	LEE ET AL.				
Office Action Summary	Examiner	Art Unit				
	Michelle Estrada .	2823				
The MAILING DATE of this communication app Period for Reply	ears on the cover sheet with the c	orrespondence addres	S			
A SHORTENED STATUTORY PERIOD FOR REPLY THE MAILING DATE OF THIS COMMUNICATION. - Extensions of time may be available under the provisions of 37 CFR 1.13 after SIX (6) MONTHS from the mailing date of this communication. - If the period for reply specified above is less than thirty (30) days, a reply - If NO period for reply is specified above, the maximum statutory period w - Failure to reply within the set or extended period for reply will, by statute, Any reply received by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b).	36(a). In no event, however, may a reply be tin within the statutory minimum of thirty (30) day will apply and will expire SIX (6) MONTHS from cause the application to become ABANDONE	nely filed rs will be considered timely. the mailing date of this commur D (35 U.S.C. § 133).	nication.			
Status						
1) Responsive to communication(s) filed on 28 Fe	ebruary 2005.					
2a)⊠ This action is FINAL . 2b)□ This	action is non-final.		•			
3) Since this application is in condition for allowar	nce except for formal matters, pro	osecution as to the me	rits is			
closed in accordance with the practice under E	x parte Quayle, 1935 C.D. 11, 45	53 O.G. 213.				
Disposition of Claims						
4) Claim(s) 1-26 is/are pending in the application.	☑ Claim(s) <u>1-26</u> is/are pending in the application.					
4a) Of the above claim(s) <u>17-20 and 26</u> is/are w	4a) Of the above claim(s) <u>17-20 and 26</u> is/are withdrawn from consideration.					
5) Claim(s) is/are allowed.	·					
6)⊠ Claim(s) <u>1-4,21 and 24</u> is/are rejected.						
7) Claim(s) <u>5-16,22,23 and 25</u> is/are objected to.						
8) Claim(s) are subject to restriction and/or	r election requirement.					
Application Papers						
9) The specification is objected to by the Examine	r.					
10)☐ The drawing(s) filed on is/are: a)☐ acce	epted or b) \square objected to by the ${ t B}$	Examiner.				
Applicant may not request that any objection to the	drawing(s) be held in abeyance. See	e 37 CFR 1.85(a).				
Replacement drawing sheet(s) including the correcti	ion is required if the drawing(s) is obj	jected to. See 37 CFR 1.	121(d).			
11)☐ The oath or declaration is objected to by the Ex	aminer. Note the attached Office	Action or form PTO-1	52.			
Priority under 35 U.S.C. § 119			·			
12) Acknowledgment is made of a claim for foreign	priority under 35 U.S.C. § 119(a))-(d) or (f).				
a) ☐ All b) ☐ Some * c) ☐ None of:						
1. Certified copies of the priority documents	s have been received.					
2. Certified copies of the priority documents	s have been received in Applicati	on No				
3. Copies of the certified copies of the prior	ity documents have been receive	ed in this National Stag	e			
application from the International Bureau	ı (PCT Rule 17.2(a)).					
* See the attached detailed Office action for a list of	of the certified copies not receive	ed.				
	*					
Attachment(s)						
1)	4) ∐ Interview Summary Paper No(s)/Mail Da					
2) Indice of Draftsperson's Patent Drawing Review (PTO-948) 3) Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08)		atent Application (PTO-152))			
Paper No(s)/Mail Date <u>2/28/05</u> .	6) 🔲 Other:					

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DETAILED ACTION

Applicant's arguments with respect to claims 1-4, 21 and 24 have been considered but are most in view of the new ground(s) of rejection.

Information Disclosure Statement

The information disclosure statements (IDS) submitted on 2/28/05 have been considered by the examiner.

Claim Rejections - 35 USC § 103

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

Claims 1-4, 21 and 24 are rejected under 35 U.S.C. 103(a) as being unpatentable over Okada et al. (6,534,397) in view of Kazuhiko (JP60235428).

With respect to claim 1, Okada et al. disclose forming an insulation film (13/14/15) on a substrate (11); forming a photoresist pattern (18) on the insulation film (Col. 10, lines 35-40); performing a first etching process (Fig. 2F) comprising etching the insulation film using the photoresist pattern as a mask to form an initial trench (20) in the insulation film (Col. 10, lines 44-50); and subsequently performing a second etching process that is distinct from said first etching process, said second etching process

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comprising etching the insulation film in which the initial trench (20) has already been formed to thereby enlarge the initial trench (Col. 11, lines 39-45).

Okada et al. do not disclose that said second etching process being a wet etching process.

Kazuhiko discloses forming a hole (7) in a substrate (1) by a dry etching process, and allowing the hole to extend through the substrate by a chemical etching process (wet etching) (See abstract).

It would have been within the scope of one of ordinary skill in the art to combine the teachings of Okada et al. and Kazuhiko to enable the second etching step of Okada et al. to be performed according to the teachings of Kazuhiko because one of ordinary skill in the art would have been motivated to look to alternative suitable methods of performing the disclosed second etching step of Okada et al. and art recognized suitability for an intended purpose has been recognized to be motivation to combine. See MPEP 2144.07.

With respect to claim 2, Okada et al. disclose further comprising removing the photoresist pattern after the initial trench is formed and prior to the second etching process (Col. 11, lines 3-10).

With respect to claim 3, Okada et al. disclose wherein said enlarging the initial trench comprises increasing a width of the initial trench while maintaining a depth of the initial trench (See Fig. 2H and 2I).

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With respect to claim 4, Okada et al. disclose wherein said forming of the insulation film comprises forming one of an oxide and a fluoride film on the substrate (Col. 3, lines 5-6).

With respect to claim 21, Okada et al. disclose forming an insulation film (13/14/15) on a substrate (11); forming a photoresist pattern (18) on the insulation film (Col. 10, lines 35-40); performing a first etching process (Fig. 2F) comprising etching the insulation film using the photoresist pattern as a mask to form an initial trench (20) in the insulation film (Col. 10, lines 44-50); and subsequently performing a second etching process that is distinct from said first etching process, said second etching process comprising etching the insulation film in which the initial trench (20) has already been formed to thereby enlarge the initial trench (Col. 11, lines 39-45); and depositing a conductive material in the enlarged trench to form a conductive pattern (26) in the insulation film (Col. 11, line 63-Col. 12, line 21).

With respect to claim 24, Okada et al. disclose wherein said material deposited in the enlarged trench comprises copper (Col. 11, line 65).

Allowable Subject Matter

Claims 5-16, 22, 23 and 25 are objected to as being dependent upon a rejected base claim, but would be allowable if rewritten in independent form including all of the limitations of the base claim and any intervening claims.

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The following is a statement of reasons for the indication of allowable subject matter: there is no disclosure in the prior art of the limitations recited in claims 5-16, 22, 23 and 25.

Conclusion

Applicant's amendment necessitated the new ground(s) of rejection presented in this Office action. Accordingly, **THIS ACTION IS MADE FINAL**. See MPEP § 706.07(a). Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will the statutory period for reply expire later than SIX MONTHS from the date of this final action.

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2800.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Michelle Estrada whose telephone number is 571-272-

1858. The examiner can normally be reached on Monday through Friday.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Olik Chaudhuri can be reached on 571-272-1855. The fax phone number

for the organization where this application or proceeding is assigned is 703-872-9306.

Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the receptionist whose telephone number is 571-272-

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

> Gedrge Fourson Primary Examiner

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May 16, 2005